Express Mail No.: <u>EV374985861US</u>

PATENT

H0003762-1170

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Chien-Wei Li

Serial No.: Filed herewith Filing Date: Filed herewith

For: ATOMIC LAYER DEPOSITION FOR

TURBINE COMPONENTS

COMMENTARY RE INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In accordance with 37 CFR §1.56, and in recognition of his duty to disclose to the United States Patent and Trademark Office relevant information known to be material to patentability, Applicant identifies the prior art listed on the attached Information Disclosure Statement (Form PTO-1449). The statement is not a representation that all of the information cited is necessarily effective as prior art against the application. Only copies of non US patents and patent applications are enclosed, if any.

Applicant respectfully requests that the disclosed reference be made of record in the subject application.

Dated: January / 4, 2004

Respectfully submitted,

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Attorneys for Applicant

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PTO/SB/08A (10-01)

Approved for use through 10/31/2002, OMB 0651-0031
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				Application Number	filed herewith	
INFO	DRMATION D	DISC	LOSURE	Filing Date	filed herewith	
STA	TEMENT BY	APF	PLICANT	First Named Inventor	LI, Chien-Wei	
				Group Art Unit		
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Sheet	1	of	2	Attorney Docket Number	H0003762-1170	

				U.S. PATENT	DOCUMENTS	·	
		Document Number				Pages, Columns, Lines	
Examiner	Cite		er – Kind Code² (if	Publication Date	Name of Patentee or Applicant	Where Relevant	
Initials*	No. ¹	known)		MM-DD-YYYY	of Cited Document	Passages or Relevant Figures Appear	
	11	US-	6,585823	07-01-2003	VAN WIJCK		
	2	US-	2003-0059633 A1	03-27-2003	ACKERMAN et al.		
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	5	US-	6,492038 B1	12-10-2002	RIGNEY et al.		
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	FO	REIGN PATENT	OCUMENTS		
0''	Foreign Patent Document			Pages, Columns, Lines	
No. 1	Country Code ³ 'Number ⁴ Kind Code ³ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Where Relevant Passages or Relevant Figures Appear	τ⁵
13	WO 03/058734 A1	07-17-2003	CHAN, Chung M., et al.		4
		Cite No. 1 Country Code 3 Number 4 Kind Code 4 (if known)	Foreign Patent Document Cite No. 1 Country Code 3 Number 4 Kind Code 3 (If known) Publication Date MM-DD-YYYY	Cite No. 1 Country Code 3 Number 4 Kind Code 3 (if known) Publication Date MM-DD-YYYY Applicant of Cited Document	Foreign Patent Document Cite No. 1 Country Code 3 Number 4 Kind Code 4 (if known) Publication Date MM-DD-YYYY Publication Date MM-DD-YYYY Applicant of Cited Document Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear

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¹Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent documents. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard St.16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

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				Group Art Unit		
(use as many sheet as necessary)				Examiner Name		
Sheet	2	of	2	Attorney Docket Number	H0003762-1170	

		OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No. 1	Include name of the author (in CAPITAL LETTERS), title of the article (when Appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T 2
	14	RITALA, Mikko, et al., Atomic Layer Deposition, Handbook of Thin Film Materials, October 2001, Volume 1, Chapter 2; San Diego, U.S.	
	15	SNEH, Ofer, et al.; Thin Film Atomic Layer Deposition Equipment for Semiconductor Processing; Thin Solid Films 402 (2002); pp. 248-261	
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Examiner	Date
Signature	Considered

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